## CONTENTS

mechanical models.

**Boginskaya I. A., Gusev A. V. Mailian K. A., Meshkov A. S., Pebalk A. V., Ryzhikov I. A., Chvalun S. N.** *Polymer Films on Based Poly-p-Ksylylene in Micro- and Optoelectronics.* 17 Technology of creation of polymer coating on based poly-p-ksylylene and chlorine modified poly-p-ksylylene on uneven substrate surface is developed. Coating with thickness 50 nm - 50 µm is obtained by vapor deposition polymerisation (VDP) method. Poly-p-ksylylene coating possess by humidity resistance, optical transparent, mechanical and electric strength, chemically inertness for most solvents, acids, and other outstanding properties. In thin poly-p-ksylylene film is obtained temperature resistance dependence with violently nonlinear character; hence, it can be used as thermo sensor. Film of poly-p-ksylylene can well be used as humidity resistance coating for optical and electronic devices.

**Keywords:** polymer films, poly-p-ksylylene, protective coating, temperature resistance dependence, thermo sensor

**Keywords:** nanocomposite, organoclay, polyethylene, "effective particle", interfacial adhesion

**Keywords:** electroelastictransducer, control systems for deformation, nano- and microdisplacements, absolute stability

The model of limit phase boundary is offered as structural second-order phase transition, which corresponds to the border of section of phases with the infinitesimal changes of parameters of crystalline grate. On the example of ferroelastic  $BiVO_4$  we obtained the equalizations of limit phases boundaries forming four orientation states are got.

Keywords: equalization of phase boundary, seconf-order phase transition, BiVO<sub>4</sub>

– НАНО- И МИКРОСИСТЕМНАЯ ТЕХНИКА, № 5, 2010 –

**Keywords:** superminiature micromechanical multifunction the sensor of the inertial information, equations of motion, finite-element models, strained-deformed state, temperature and technological errors

## For foreign subscribers:

Journal of "NANO and MICROSYSTEM TECHNIQUE" (Nano- i mikrosistemnaya tekhnika, ISSN 1813-8586)

The journal bought since november 1999. Editor-in-Chief Ph. D. Petr P. Maltsev

ISSN 1813-8586.

Address is: 4, Stromynsky Lane, Moscow, 107076, Russia. Tel./Fax: +7(499) 269-5510. E-mail: nmst@novtex.ru; http://www.microsystems.ru

Адрес редакции журнала: 107076, Москва, Стромынский пер., 4. Телефон редакции журнала (499) 269-5510. E-mail: nmst@novtex.ru Журнал зарегистрирован в Федеральной службе по надзору за соблюдением законодательства

в сфере массовых коммуникаций и охране культурного наследия.

Свидетельство о регистрации ПИ № 77-18289 от 06.09.04.

Дизайнер Т. Н. Погорелова. Технический редактор Е. М. Патрушева. Корректор Е. В. Комиссарова

Сдано в набор 16.03.2010. Подписано в печать 19.04.2010. Формат 60×88 1/8. Бумага офсетная. Печать офсетная. Усл. печ. л. 6,86. Уч.-изд. л. 8,30. Заказ 376. Цена договорная

Отпечатано в ООО "Подольская Периодика", 142110, Московская обл., г. Подольск, ул. Кирова, 15

– НАНО- И МИКРОСИСТЕМНАЯ ТЕХНИКА, № 5, 2010 –